

fluids and for deriving signals thereof.--

The paragraph beginning at line 9 of page 5 is to be replaced by the following rewritten paragraph:

--In the accomplishment of these and other objects, the invention provides for a sensor for viscosity measurements in small fluid volumes without fluid consumption, and for methods of fabricating a miniaturized sensor suitable for carrying out such measurements, including affinity viscometry.--

The paragraph beginning at line 4 of page 8 is to be replaced by the following rewritten paragraph:

--In an alternate embodiment of the invention, at least one movable cantilevered conductor is positioned in the effective field of a permanent magnet such that the flux lines thereof extend substantially normal to the main directional movement of the conductor.--

Line 4 of page 9 is to be rewritten as follows:

--Fig. 2 is a sectional view on an enlarged scale along line II - II of Fig. 1.--

The paragraph beginning at line 13 of page 11 is to be replaced by the following rewritten paragraph:

--As regards the fabrication of the apparatus described, the structuring of the measuring zone and the movable loop 3 is significant. In accordance with the invention, the movable loop 3 is fabricated only after formation of all active and passive components of the integrated circuit of the viscosity sensor has been completed, by applying an additional photo lithographically structured lacquer mask prior to opening the passivation windows and separation of the sensor chips produced on a semiconductor substrate (wafer). The mask serves, by a localized isotropic insulator etching process, to undercut and completely